# Non-Uniform matching performances in mesa-isolated SOI MOSFETs

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Abstract— This work studies the threshold voltage mismatch of mesa-isolated SOI pMOSFETs through a breakdown between edge and center contributions. Pelgrom's law is followed if a proper care is taken in the Vt extraction method. Applied to pMOS devices we observed that despite its parasitic nature, the edge transistor mismatch is as good as that of the center, regardless of channel doping. Even more, the edge mismatch appears to be less degraded when a positive bias is applied to the back-gate.

#### I. INTRODUCTION

Mismatch in MOSFET transistors plays a crucial role in circuit design [1]. With the scaling down of analog technologies driven by low power application, mismatch origin and modelling have been widely discussed. However, in some specific cases, such as junctionless transistors [2] or mesa-isolated devices, the presence of a parasitic transistor makes a straightforward Vt matching study incomplete. In this context, we discuss a methodology to properly assess the device mismatch and compare main and parasitic transistor performances in our SOI mesa-isolated pMOSFETs.

### II. DEVICE DESCRIPTION & METHODOLOGY

SOI pMOS are defined for 2.5V applications such as sensing with channel thickness  $t_{si} = 23nm$ , burried oxide thickness  $t_{box} = 25nm$  and SiO2-Polysilicon gate stack with EOT=6nm. Channel is undoped or doped (8e17at/cm<sup>3</sup>, 1.5e18 at/cm<sup>3</sup>) to allow multi Vt offer. Due to the mesa isolation, the gate stack covers the complete silicon film, including the edge as shown by TEM cross section on Fig. 1. It was shown in [3] that there are two distinct conduction regimes, one at the edges and one at the center. Thus, the entire device can be modeled as two transistors in parallel. Measurements consisted of Id-Vg curves in linear regime (Vd=50mV) for three ground plane biases (Vb=-2.5V, 0V, 5V). We measure the Vt standard deviation of pairs of matched transistors  $\sigma_{\Delta Vt}$  (layout view on Fig. 1.B). Overall devices widths (Wdrawn) and lengths (L) range from 0.2µm to 25µm.

## III. RESULTS AND DISCUSSION

The edge transistor resulting from the mesa-isolation creates a hump in the Id-Vg curve (Fig. 2.a), highlighted in the gm/Id curve where the highest peak comes from the edge transistor. The edge transistor is always present but not necessarily visible, as demonstrated by the single peak on gm/Id in the undoped channel case (Fig2.b). This stems from the different scaling of each transistor Vt with channel doping and back-gate bias (Fig. 2.b and 2.c). Having identified this issue, it is clear that proper care must be taken in the Vt extraction before getting to mismatch. The most straightforward methods such as extrapolation in the linear region or constant current at  $10^{-7}W/L$  do not discriminate between the different regimes. Vt can be that of the edge transistor, of the center, or a mix of both depending on the geometry. The ratio method however [4], applied separately to each peak in the  $g_m/I_d$  curves (Fig 2) would be a suitable solution. Instead of the ratio method, in order to cover mismatch in the complete subthreshold regime, we chose to extract Vt at a constant current threshold for several points per decade. At low extraction current, Vt is that of the edge transistor and conversely, extracting at higher currents provides the center

transistor Vt. For each threshold current value, we get the corresponding  $\sigma_{\Delta V_{r}}$ , leading to Fig. 3. Two plateaus are visible, corresponding to edge and center transistors. At low extraction currents, the two devices  $W_{drawn} = 1 \mu m$  and  $W_{drawn} = 25 \mu m$  have similar  $\sigma_{\Delta V_t}$  as expected of the edge transistor, whose dimensions do not scale with the drawn width. At higher currents, there is a x5 difference in  $\sigma_{\Delta V_t}$ , corresponding to a  $1/\sqrt{WL}$  scaling (Pelgrom's law) as expected from a planar SOI transistor. We can get their respective iAvt considering the appropriate  $\sqrt{WL}$ ratio. In [3], TCAD simulations showed that the edge conduction regime extends to about 50nm on each side. Therefore, the edge transistor width is the sum of the silicon channel thickness and the 50nm extension on both sides:  $W_{edge} = 2(t_{si} + 50) = 150nm$ (Fig. 1). Complementarily, the center transistor width is W<sub>center</sub>=W<sub>drawn</sub>-(W<sub>edge</sub>+2t<sub>si</sub>). With the appropriate width and  $\sigma_{\Delta V_t}$ (Fig. 3), the resulting Pelgrom plot in figure 4 shows a linear variation of  $\sigma_{\Delta V_t}$  for both contributions. The straightforward plot with no separate normalization and extraction  $10^{-7}W/L$  is also shown for comparison (green squares). The slopes are almost identical for the two devices: same matching performance is achieved (Avt =6mV.µm) for edge and center transistors. We further expand this approach to study the impact of channel doping on center and edge transistor mismatch. Same Avt increase is observed with channel doping for both top and edge transistors, (Fig 5). Finally, we address the back-bias effect on the mismatch for different doping channel. Figure 6 displays  $\sigma_{\Delta V_t}$  for three different back-biases (V<sub>b</sub>=-2.5V, 0V, 5V). At V<sub>b</sub>=-2.5V,  $\sigma_{\Delta V_t}$  is constant on the entire current threshold range, indicating that a single transistor is measured instead of two at 0V. Thus, the apparent decrease at low extraction currents is due to a change in conduction regime. On the other hand, at Vb=+5V the two different regimes are maintained and the mismatch of both transistors increases. The increase is much higher in the case of the center transistor, hence the "reverse staircase" shape compared to V<sub>b</sub>=0V. This increase in variability for positive back-biases holds true for other dimensions, resulting in the Pelgrom plot figure 7.

## IV. CONCLUSION

We measured matching structures of different dimensions to assess the V<sub>t</sub>-matching of pMOS on SOI devices. Because of mesa isolation, a parasitic edge transistor is present. The edge transistor V<sub>t</sub>-matching is identical to that of the top transistor with an Avt of 6mV. $\mu$ m. The impact of channel doping and back bias were investigated. The back bias produced dramatic increase in the V<sub>t</sub>-matching with a larger response for the center transistor.

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